

**Correction to**

**Highly-sensitive wafer-scale transfer-free graphene MEMS condenser microphones  
(Microsystems & Nanoengineering, (2024), 10, 1, (27), 10.1038/s41378-024-00656-x)**

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CORRECTION

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# Correction: Highly-sensitive wafer-scale transfer-free graphene MEMS condenser microphones

Roberto Pezone , Sebastian Anzinger, Gabriele Baglioni, Hutomo Suryo Wasisto , Pasqualina M. Sarro, Peter G. Steeneken  and Sten Vollebregt 

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After publication of this article<sup>1</sup>, it was brought to our attention that *two pressure values* were not correctly copied from the submitted original work to the published version.

**Correction 1 (from PDF, Page 4 of 9):** “These membranes show resonance frequencies above the audible range ( $f_{01} > 20$  kHz) at  $1 \times 10^3$  mbar by piezo-shaker actuation”. The described phrase needs to be changed reporting the right pressure value of  $1 \times 10^{-3}$  mbar. The new phrase will be: “*These membranes show resonance frequencies above the audible range ( $f_{01} > 20$  kHz) at  $1 \times 10^{-3}$  mbar by piezo-shaker actuation*”.

**Correction 2 (from PDF, Page 4 of 9):** “Energy losses and dampening are minimized due to the low pressure of  $1 \times 10^3$  mbar”. Again, the described phrase needs to be changed reporting the right pressure value of  $1 \times 10^{-3}$  mbar. The new phrase will be: “*Energy losses and dampening are minimized due to the low pressure of  $1 \times 10^{-3}$  mbar*”.

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## Reference

1. Pezone, R. et al. Highly-sensitive wafer-scale transfer-free graphene MEMS condenser microphones. *Microsyst. Nanoeng.* **10**, 27 (2024).

